



Docket No. 0008-FA-US

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re Application of Hunt et al.

Group Art No. 1762 (parent)

Application No. 09/748,714

Filed: 21 December 2000

For: CHEMICAL VAPOR DEPOSITION METHODS FOR MAKING
POWDERS AND COATINGS, AND COATINGS MADE
USING THESE METHODS

Submission of Additional Fees—Large Entity Status

Assistant Secretary and Commissioner of Patents and Trademarks
Washington D.C. 20231

RECEIVED

JUN 4 2001

OFFICE OF PETITIONS

Sir:

Fees, as calculated by the NOTICE TO FILE MISSING PARTS OF
NONPROVISIONAL APPLICATION dated 23 February 2001, of \$1241 were paid on a
Small Entity basis.

It has subsequently been determined that Large Entity fees should have been paid.
It is believed that the technology which is the subject matter of this application falls
under a general technology license to a Large Entity.

Neither this application nor its parent case were specifically listed in the schedule
of patents and application attached to the license agreement.

The erroneous claim of Small Entity status was made without deceptive intent.

The patent Office is authorized to charge an additional \$1241 for filing fees and
surcharge to Deposit Account No. 501231. A duplicate copy of this letter is attached.

21 May, 2001

Wayne E. Nacker, Reg. 29,571
Customer No. 24948

I, Wayne E. Nacker, hereby certified that this document and the documents listed above were deposited with the U.S. Postal Service
on 21 May, 2001, postage paid, addressed to the Assistant Commissioner for Patents, Washington, D.C.
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05/01/2001 STEFFERA 00000003 501231 09748714

05/01/2001	710.00	CH
05/01/2001	000.00	CH
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